U.S. Serial No.: 09/966,604

Group Art Unit: 2858

ETE-025

## **AMENDMENTS TO THE CLAIMS**

Upon entry of this amendment, the following listing of claims will replace all prior versions and listings of claims in the pending application.

## IN THE CLAIMS

Please cancel claims 4 and 18 without prejudice or disclaimer of the subject matter therein.

Please amend the pending claims 1, 5, 6, 8, and 17 as follows:

1. (Currently Amended) A system for determining the presence or absence of an ion in a plasma, comprising:

an ion source having a plasma chamber sized and dimensioned for generating a plasma having an ion present therein, and

a probe assembly coupled to the ion source for detecting said ions of said plasma, the probe assembly having a probe device for extracting one or more of said ions from said plasma and a filter coupled to said probe device for filtering said one ore more ions extracted by said probe device from said plasma.

- 2. (Original) The system of claim 1, wherein said probe assembly comprises a probe device extending within the plasma chamber for extracting said ion from said plasma.
- 3. (Original) The system of claim 2, wherein the probe device comprises:
  - a probe body having a conical tip disposed within the plasma chamber, and
- a focusing element mounted to said probe body and adapted for generating a field, when energized, therein.
- 4. (Cancelled)

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5. (Currently Amended) The system of claim [4]1, wherein the filter comprises at least

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one of a Wien filter and an EXB filter.

6. (Currently Amended) The system of claim [4]1, wherein the filter comprises a plurality

of steel strips for concentrating a magnetic field within the filter.

7. (Original) The system of claim 6, wherein the plurality of steel strips are biased at

different voltages to produce one of a potential gradient and a uniform electric field

within a passageway.

8. (Currently Amended) The system of claim [4]1, further comprising means for

generating an electric field within the filter to separate one or more ions based on ion

velocity.

9. (Original) The system of claim 1, further comprising a vacuum source coupled to said

probe device for creating a selected pressure condition therein for facilitating extraction

of said ion from said plasma chamber.

10. (Original) The system of claim 1, wherein said probe assembly comprises a probe

device having a probe body, a portion of which is adapted to extend into said plasma

chamber, and a set of electrodes coupled to said probe body for creating a field therein.

11. (Original) The system of claim 1, wherein said probe assembly comprises a probe

device for extracting one or more ions from said plasma, a filter for filtering said ions,

and a controller for detecting said one or more ions.

12. (Original) A probe assembly suitable for use with an ion source for detecting an ion

in a plasma within a plasma chamber of the ion source, comprising:

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a focusing element coupled to said probe for generating a selected field within the

probe; and

a filter coupled to said probe for filtering said ion passing through said probe and

extracted from said plasma chamber.

13. (Original) The probe assembly of claim 12, wherein said probe body comprises a

passageway sized and dimensioned for allowing the ion to pass therethrough, said body

having a conical end portion that extends within the plasma chamber.

14. (Original) The probe assembly of claim 12, wherein a set of electrodes is coupled to

said probe body for creating a field therein.

15. (Original) The probe assembly of claim 14, wherein said electrodes comprise a

quadrupole focusing element for generating a field within the probe body for said ion

from said plasma chamber.

16. (Original) The probe assembly of claim 12, wherein said filter comprises an EXB

filter.

17. (Currently Amended) A method for detecting an ion within a plasma generated

within a plasma chamber of an ion source, comprising the steps of:

extracting the ion from the ion source with a probe device;

filtering the ion extracted from the ion source; and

detecting the ion extracted from the plasma chamber.

18. (Cancelled)

19. (Original) The method of claim 17, wherein the step of filter comprises the step

varying a field so as to filter the one or more ions based on ion velocity.

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20. (Original) The method of claim 17, further comprising the step of twisting a set of electrodes to produce a rotating quadrupole field that alternately focuses ions in all directions.